# LabAdviser update: 2/10 2020

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| Updated Subject  | Contributor | Link to the updated pages |
| **Thermal evaporator**QC limits included | **Rebecca B. Ettlinger @Nanolab**  | [Thin\_film\_deposition/thermalevaporator#Quality\_control\_.28QC.29\_procedure\_for\_the\_Thermal\_evaporator](http://labadviser.nanolab.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/thermalevaporator#Quality_control_.28QC.29_procedure_for_the_Thermal_evaporator) |
| **Dektak XTA**Improved part on uncertainty of Dektak measurements | **Rebecca B. Ettlinger @Nanolab**  | [Characterization/Profiler#Total\_uncertainty](http://labadviser.nanolab.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/Profiler#Total_uncertainty) |
| **Sputter deposition**New overview page on sputter deposition of metals and alloysNew overview page on sputter deposition of oxides | **Rebecca B. Ettlinger @Nanolab** | [Thin\_film\_deposition/Sputter\_deposition\_of\_metals\_and\_alloys](http://labadviser.nanolab.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Sputter_deposition_of_metals_and_alloys)[Thin\_film\_deposition/Sputter\_deposition\_of\_oxides\_and\_other\_compounds#Sputter\_deposition\_of\_oxides](http://labadviser.nanolab.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Sputter_deposition_of_oxides_and_other_compounds#Sputter_deposition_of_oxides) |
| **XPS Nexsa**New XPS tool with a lot of exciting options | **Jonas Michael-Lindhard @Nanolab** | [Characterization/XPS/NexsaOverview](http://labadviser.nanolab.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/XPS/NexsaOverview) |
| **DRIE Pegasus**Picoscope process monitoring on DRIE Pegasus tools (available on Peg 1, 2 and 3) | **Jonas Michael-Lindhard @Nanolab** | [/Etch/DRIE-Pegasus/picoscope](http://labadviser.nanolab.dtu.dk/index.php/Specific_Process_Knowledge/Etch/DRIE-Pegasus/picoscope) |

# Equipment Manuals updated in LabManager (since 18th of June):

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

**5. 3. 6.02) Manual for Saw (Disco 321), ver 1.3 02.07.2020**

**5. 3. 7.42) Manual for Nikon ECLIPSE L200 (2) optical microscope, ver 2.4 14.09.2020**

**5. 3. 7.26) Manual for SEM Supra 1, ver 6.2 03.07.2020**

**5. 3. 3.10) Manual for III-V ICP, ver 1.6 26.08.2020**

**5. 3. 2.23) Manual for PECVD4, ver 1.3 26.08.2020**

**5. 3. 7.57) Manual for XPS Nexsa, ver 1 23.09.2020**

**5. 3. 3.04) Manual for AOE, ver 3.6 26.08.2020**

**5. 3. 2.25) Manual for Thermal Evaporator, ver 1.3 26.08.2020**

**5. 3. 3.11) Manual for ICP Metal Etch, ver 2.5 26.08.2020**

**5. 3. 7.45) Manual for ellipsometer VASE, ver 1.5 28.08.2020**

**5. 3. 1.58) Manual for Aligner: Maskless 03, ver 2.1 22.06.2020**

**5. 3. 3.05) Manual for ASE, ver 2.3 10.07.2020**

**5. 3. 3.13) Manual for HF and BHF in various dedicated baths, ver 8 21.09.2020**

**5. 3. 5.06) Manual for Anneal-Bond furnace (C3), ver 7 23.09.2020**

**5. 3. 5.13) Manual for BCB Curing Oven, ver 2.3 29.06.2020**